

Picosecond Laser Processing Machine

Equipment Precision:

- Overall processing precision: $\pm 20 \mu\text{m}$
- X-Y stage positioning precision: $\pm 3 \mu\text{m}$
- X-Y stage repeatability: $\pm 1 \mu\text{m}$
- Laser focal position precision: $5 \mu\text{m}$
- Camera recognition precision: $6 \mu\text{m}$

Processing Performance:

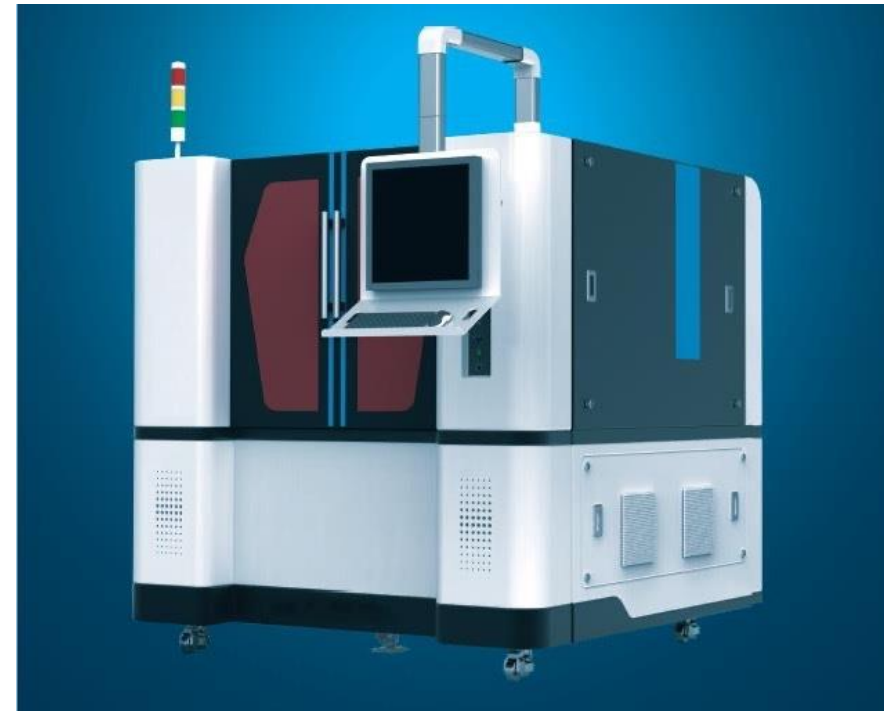
- Effective table size: $590 \text{ mm} \times 550 \text{ mm}$
- Stroke range: $750 \text{ mm} \times 750 \text{ mm}$
- Maximum table travel speed: 900 mm/s
- Maximum galvanometer scan speed: 3000 mm/s
- Spot diameter: $15 \mu\text{m}$

Laser Source:

- Wavelength: 355 nm
- Maximum output power: 30 W
- Pulse width: 10 ps
- Variable frequency range: $301\text{--}2000 \text{ kHz}$

Dimensions & Weight:

- Dimensions (W×D×H): $1600 \text{ mm} \times 1600 \text{ mm} \times 2200 \text{ mm}$
- Weight: Approx 2000 kg



Laser Processing Equipment

Integrates optical, mechanical, electrical and numerical control systems

Includes laser source, optical system, motion platform, image positioning & control system

Complete and versatile processing workstation

Supported Laser Types

Industrial lasers

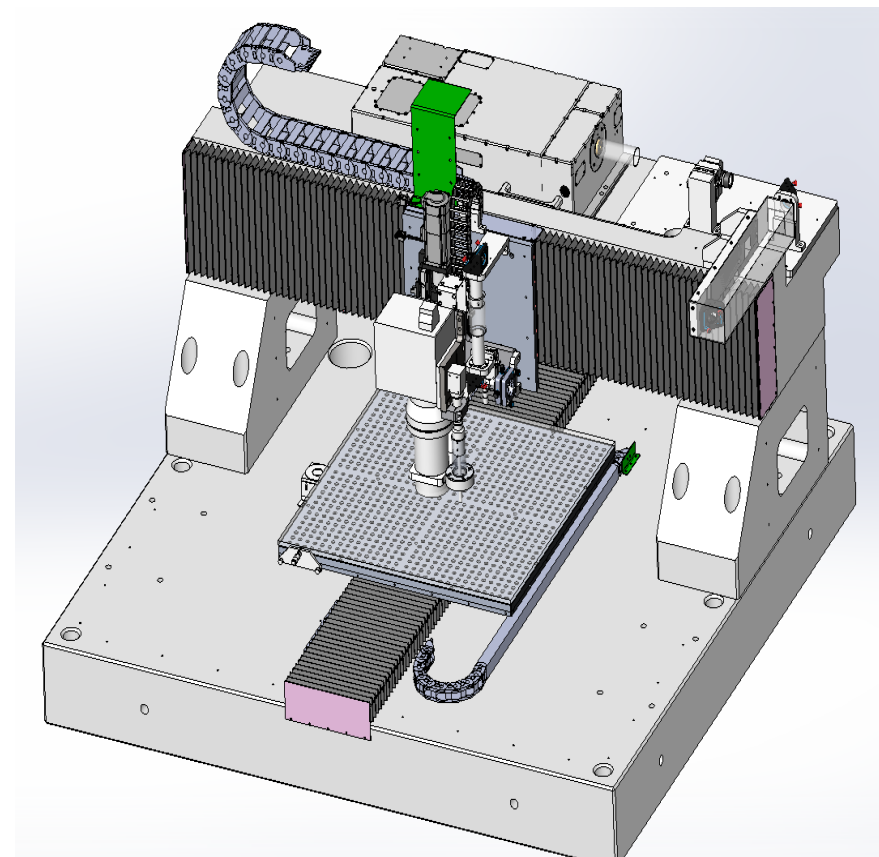
Semiconductor lasers

Fiber lasers

Solid-state nanosecond lasers

Solid-state picosecond lasers

CO₂ lasers



Cold Processing

Picosecond lasers emit ultrashort pulses (~ 10 ps) with minimal thermal impact

Cold ablation delivers smoother cuts, less dust, and higher efficiency

Short pulses minimize heat-affected zones and enable precise micromachining

Available Wavelengths & Materials

UV 355 nm: PI materials, copper foil, silicon wafers, flexible boards

Green 532 nm: brittle materials such as toughened glass and ceramics

IR 1050–1070 nm: non-strengthened glass and metal plates



Edgewave InnoSlab PX Series

Beam quality: $M^2 < 1.5$

Repetition frequency: up to 2.0 MHz

Pulse width: 10 ps

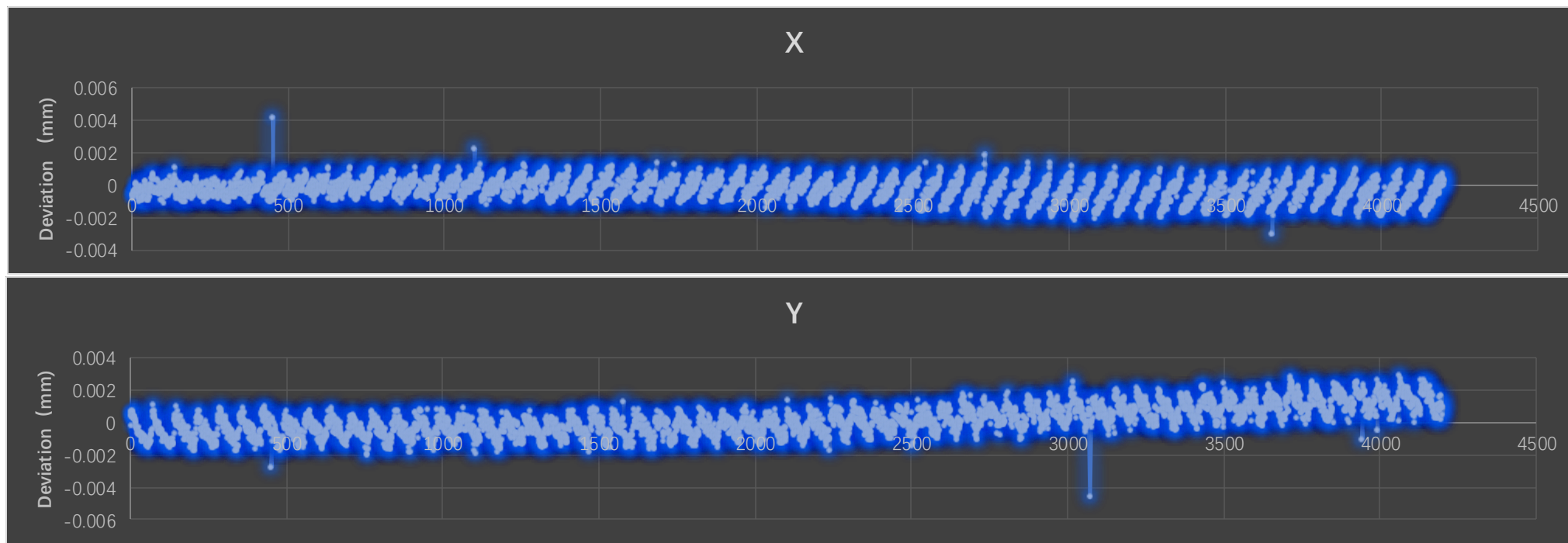
Beam divergence: $< 200 \mu\text{rad}$

High-Precision Motion Control

Linear motors in X & Y form a 2D motion platform

Calibrated using a high-precision board, achieving $\approx 3 \mu\text{m}$ motion accuracy

Telecentric lens + CMOS camera deliver distortion-free imaging and $5 \mu\text{m}$ positioning precision

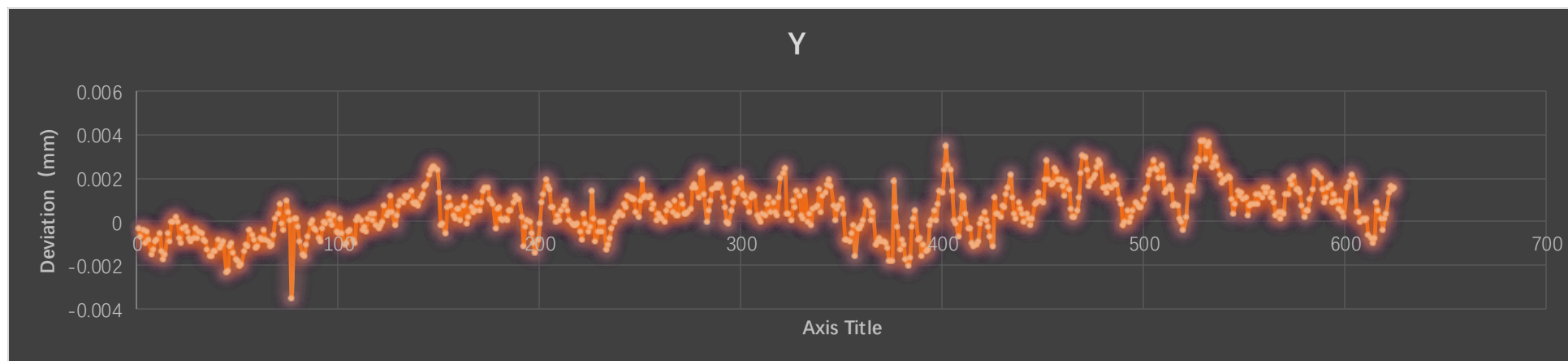
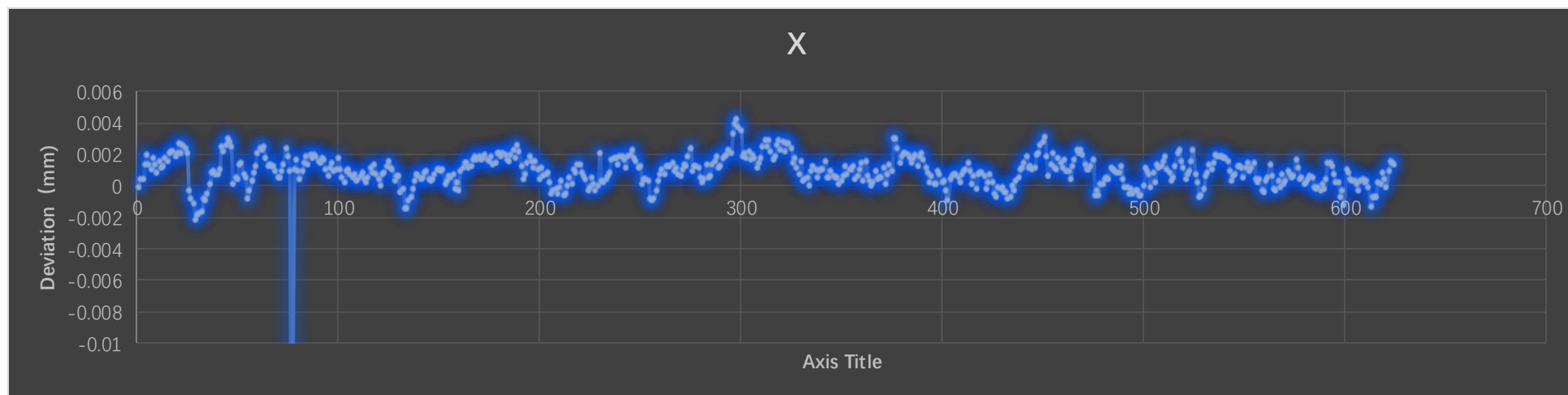


High-Precision Scan Control

German-made calibration software calibrates the galvanometer

Achieves $\pm 5 \mu\text{m}$ system positioning accuracy (platform + galvanometer + camera)

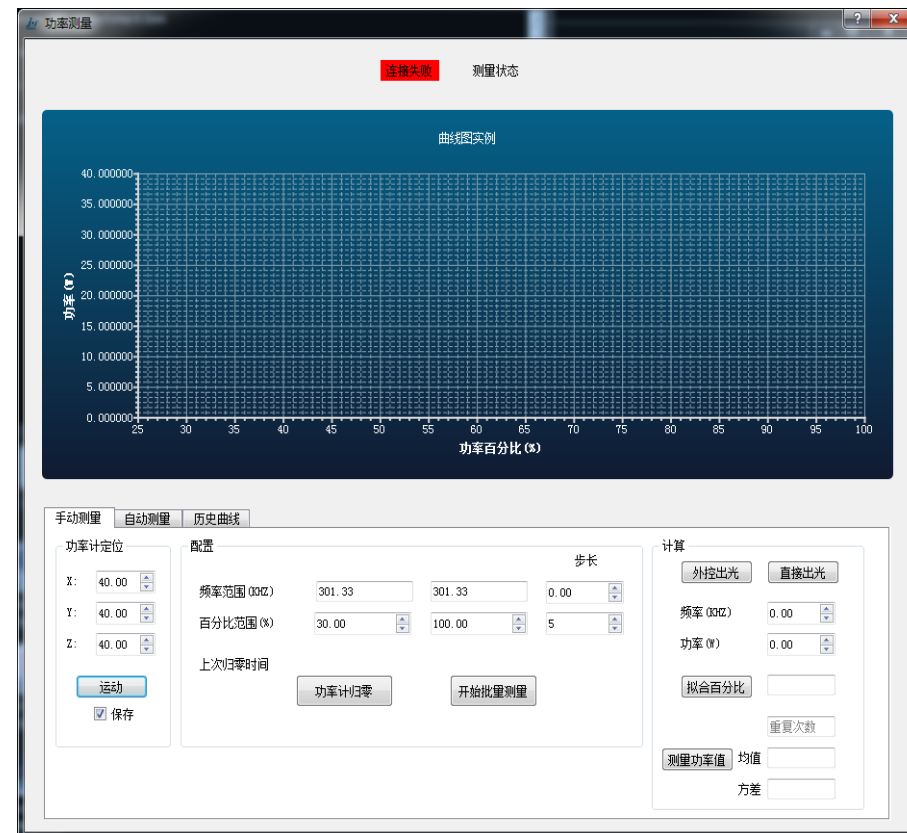
Ensures high scan precision and uniform performance



Fully Automated Processing

User-friendly software controls the entire process

- Import processing path files generated by CAM.
- Set the necessary laser parameters, feed speeds, and scan speeds for processing.
- Use the camera system to determine the position of alignment points and complete alignment and coordinate system transformation of the workpiece.
- Select the processing area using the numerical control software virtual platform window and begin process.
- Measure and calibrate laser output to ensure uniform processing quality.
- Use the Step & Repeat processing mode; however, with high-precision motion control and high-precision scan control, continuous seam-free processing can be completed without setting overlap areas.

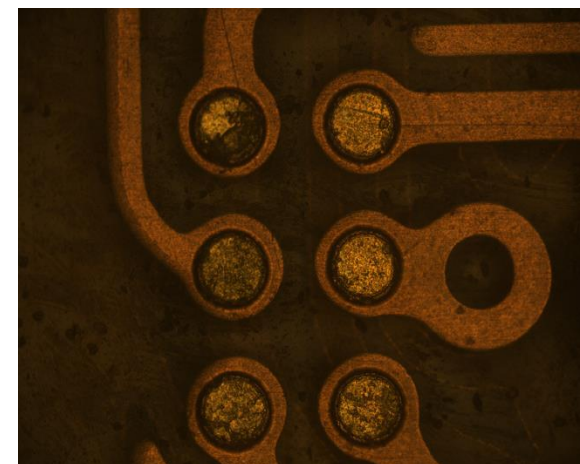
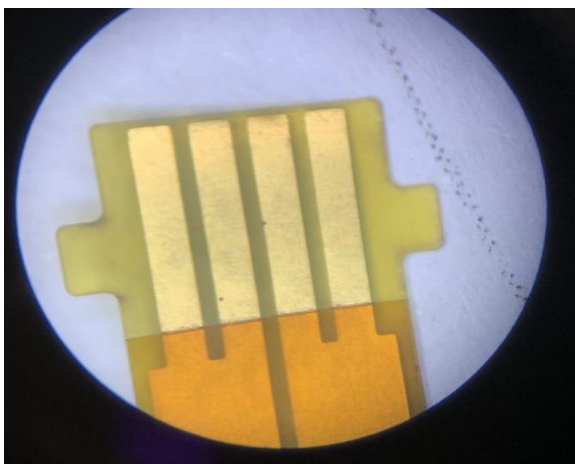


Applications of Picosecond Lasers

Cutting flexible printed circuits (FPC)

Drilling holes in smartphone glass and displays

Grooving and scribing for microelectronics



Please contact us below for more information.

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